

Amendments to the Claims

1. (Currently Amended) A vacuum deposition apparatus comprising:
a susceptor for heating a glass substrate ~~a portion of the susceptor~~
~~providing an area used as a sliding portion on which to slide the glass~~
~~substrate to a desired position the susceptor being used for generating plasma;~~
a lift pins for supporting ~~said the~~ glass substrate on the susceptor;
a robot arm for transferring the glass substrate ~~onto the susceptor to~~ and
returning the glass substrate from the susceptor; ~~and~~
a stopper pin for indicating an end of the susceptor; and
a groove formed in ~~said portion a slide part of the susceptor for receiving~~
~~and into which a film-forming material scraped from a surface of the susceptor~~
~~by a leading edge of the glass substrate during sliding of is generated by~~
~~friction between the substrate and the susceptor when the substrate is inclined~~
~~for placing the glass substrate on the surface of the susceptor.~~

2. (Currently Amended) The vacuum deposition apparatus according
to claim 1, wherein a gap between ~~an end a beginning of said portion of said~~
substrate and ~~said groove stopper pin is~~ at least 3 mm, ~~the beginning of said~~
~~portion being the position on the susceptor where the leading edge of the glass~~
~~substrate first touches the susceptor during sliding.~~

3. (Currently Amended) The vacuum deposition apparatus according to claim 2, wherein ~~the said gap~~ is 10 mm.

4. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the susceptor is made of a quartz material.

5. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the section of said groove formed in the ~~slide part sliding~~ portion has a polygonal configuration.

6. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the bottom face of the groove formed in the ~~slide part~~ sliding portion has a curved configuration.

7. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the bottom face of the groove formed in the ~~slide part~~ sliding portion includes an incline plane and a perpendicular plane.

8. (Currently Amended) The vacuum deposition apparatus according to claim 1, wherein the groove formed in the ~~slide part sliding portion~~ has a V-shaped configuration.